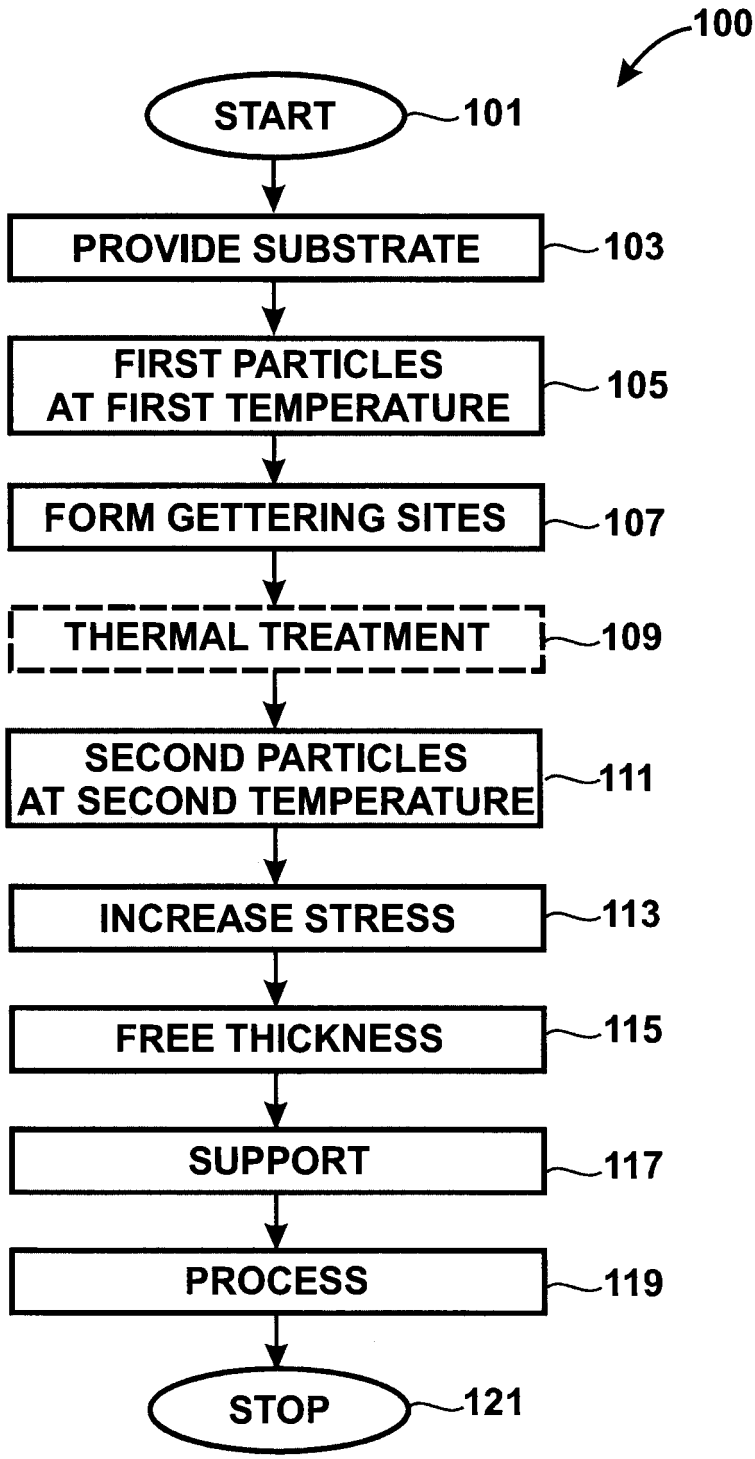

100
START
101
PROVIDE SUBSTRATE
103
FIRST PARTICLES AT FIRST TEMPERATURE
105
FORM GETTERING SITES
107
THERMAL TREATMENT
109
SECOND PARTICLES AT SECOND TEMPERATURE
111
INCREASE STRESS
113
FREE THICKNESS
115
SUPPORT
117
PROCESS
119
STOP
121

FIGURE 1

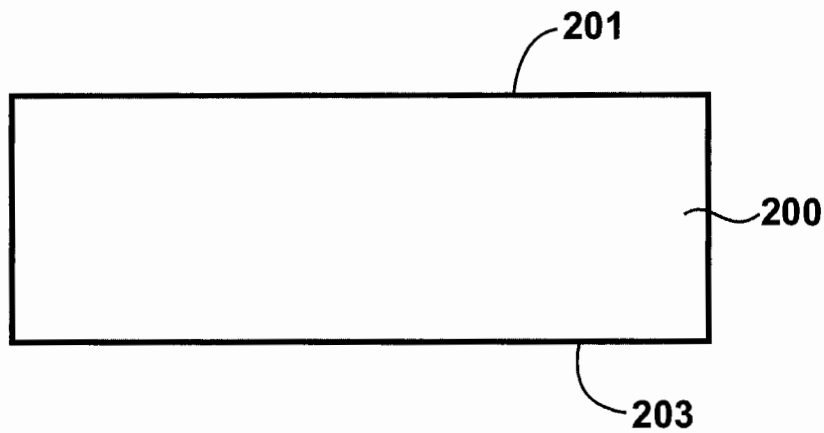


FIGURE 2

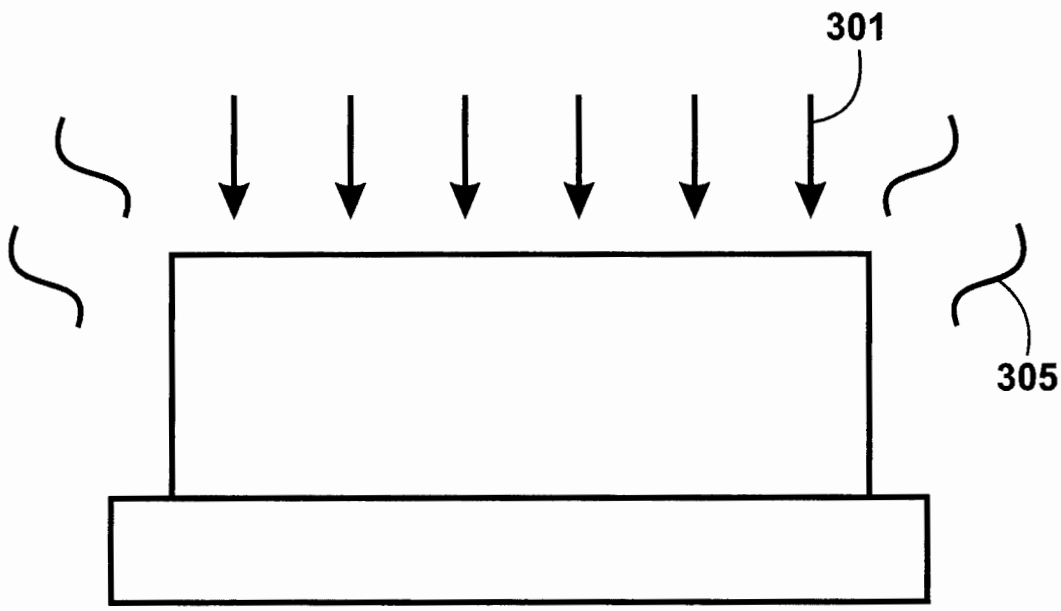


FIGURE 3

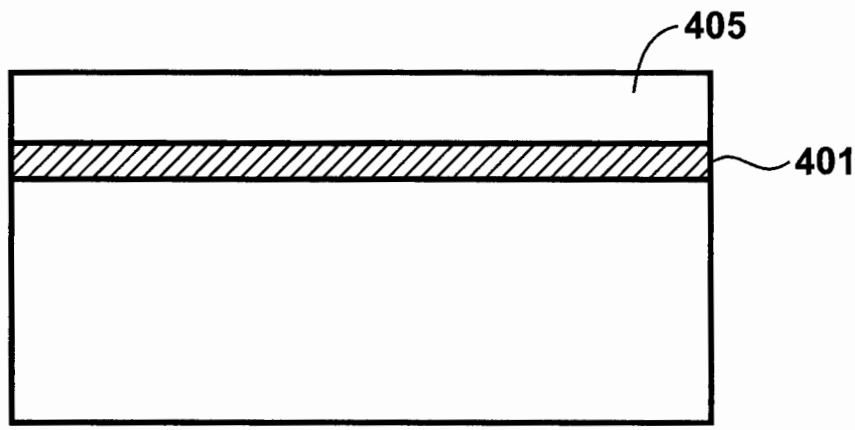


FIGURE 4

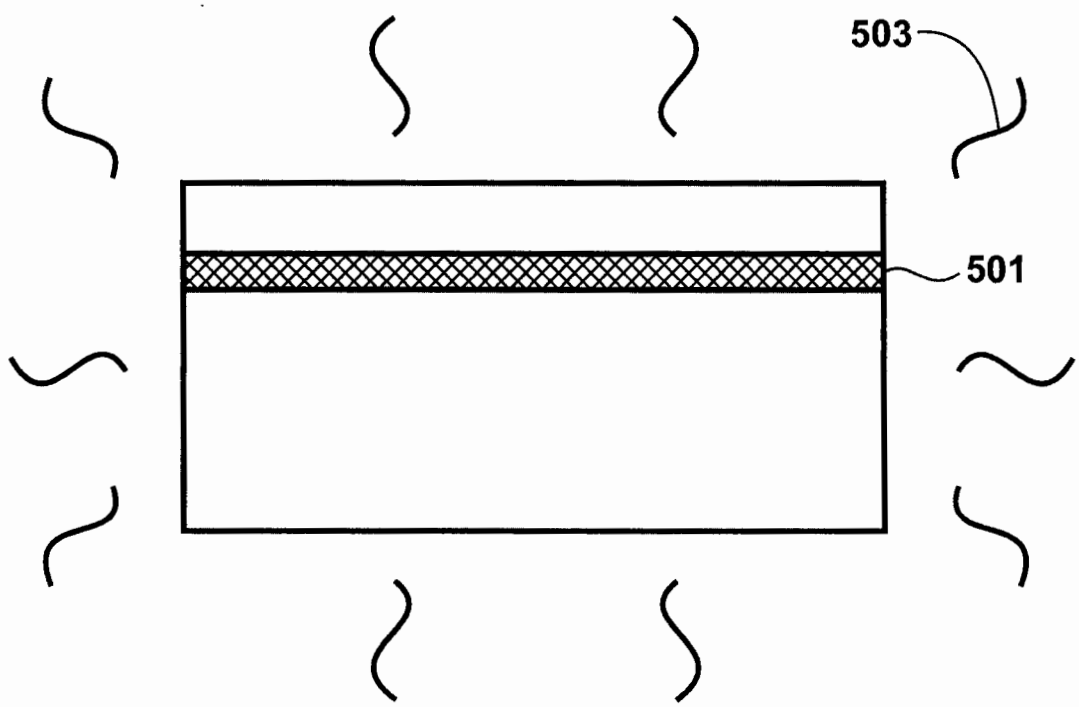


FIGURE 5

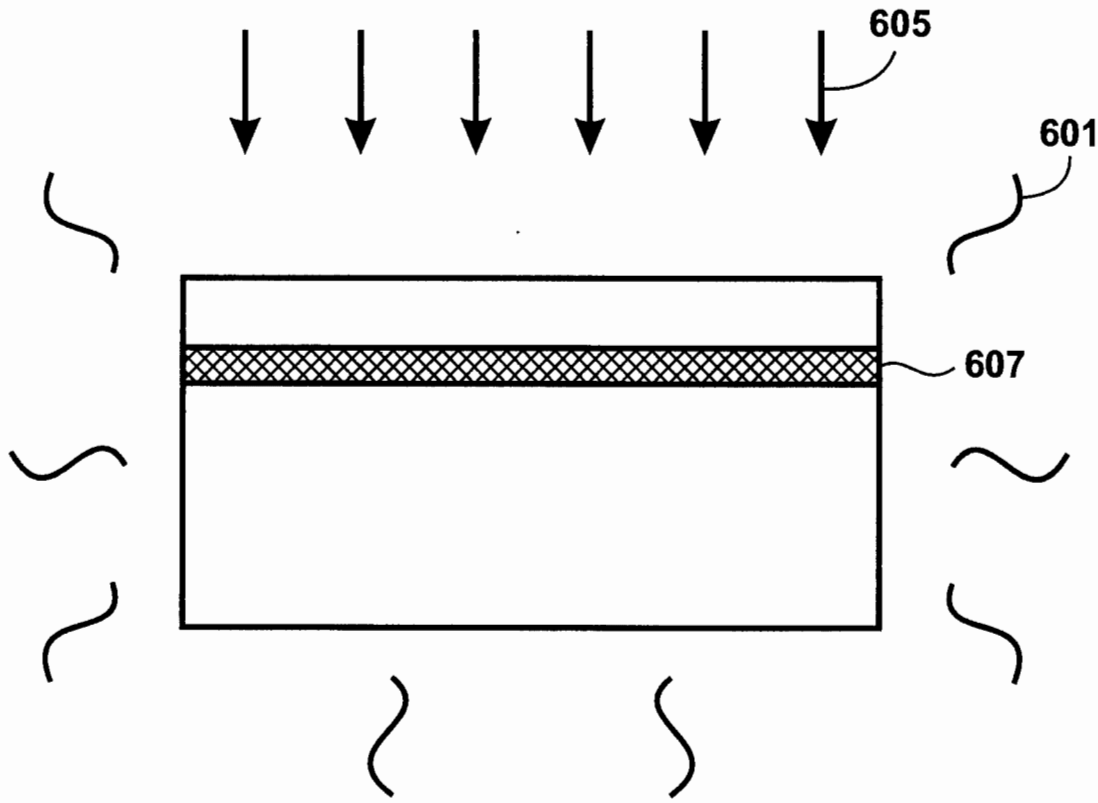


FIGURE 6

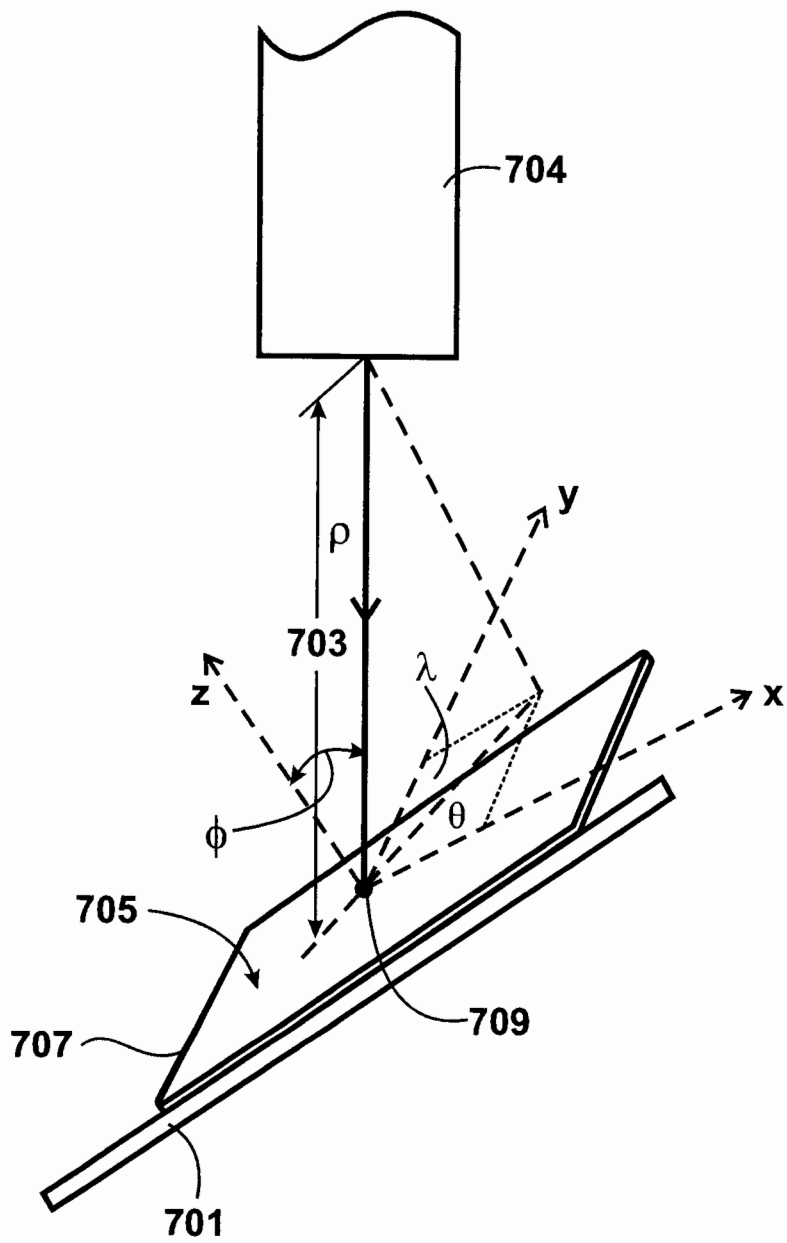


FIGURE 7

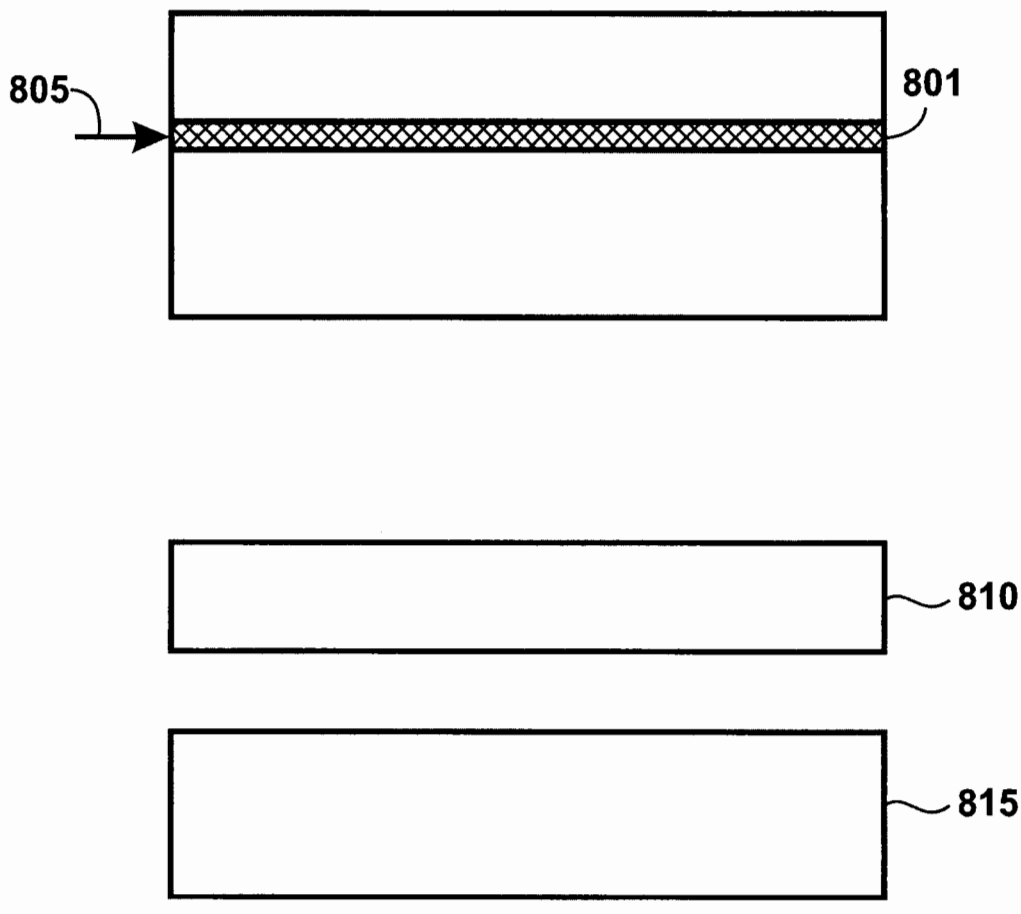


FIGURE 8

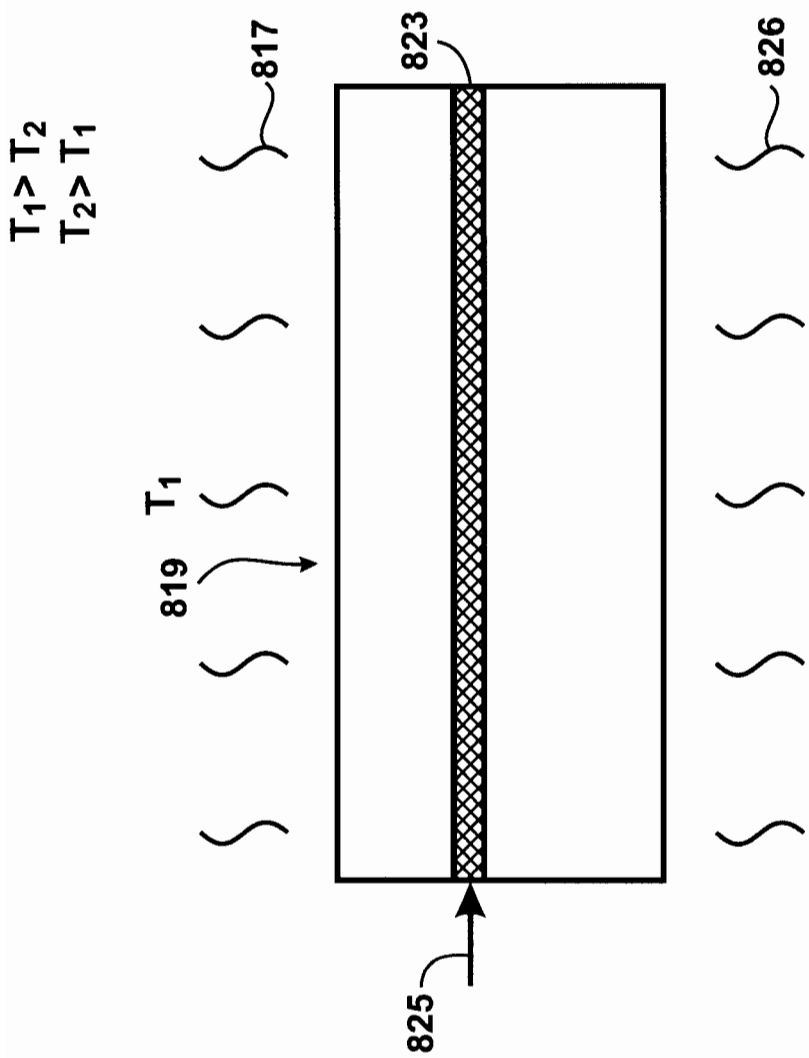


FIGURE 8A

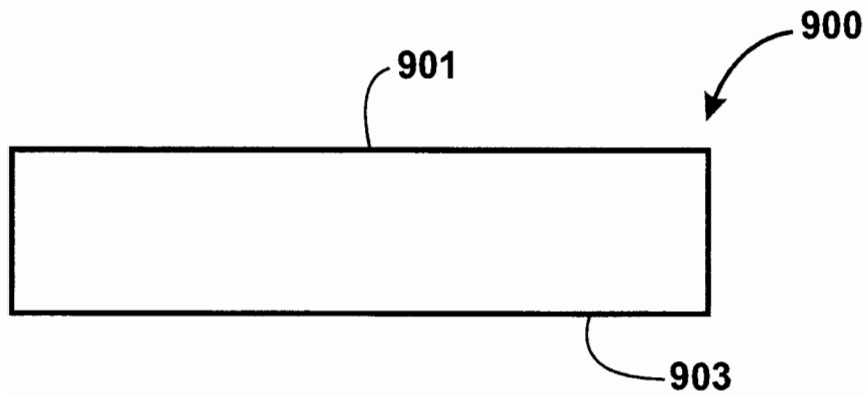


FIGURE 9

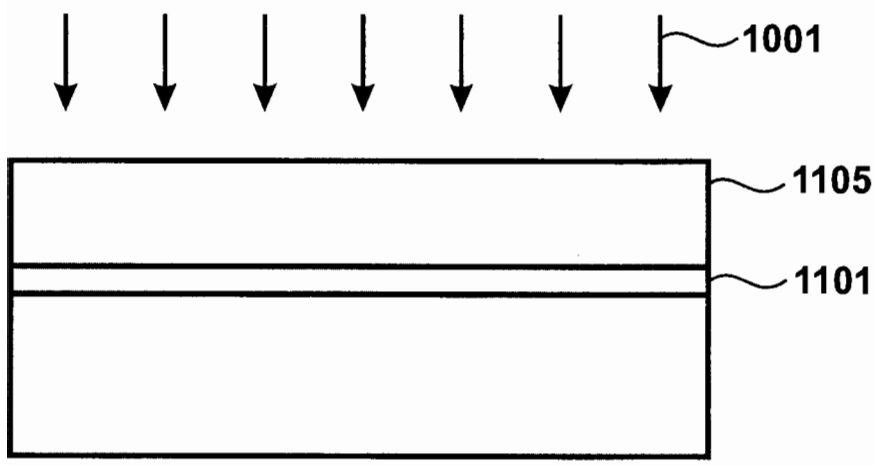


FIGURE 10

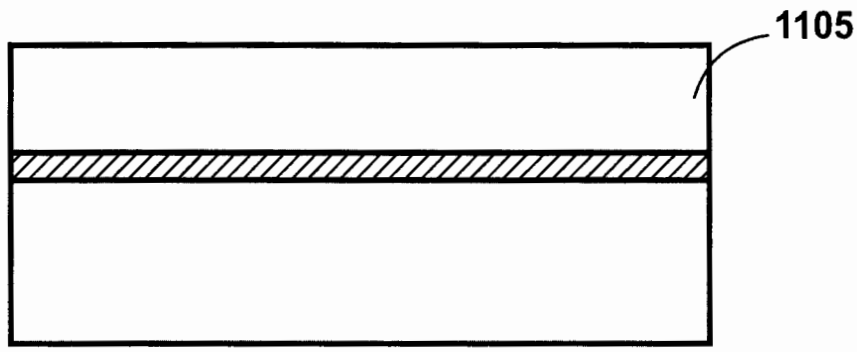


FIGURE 11

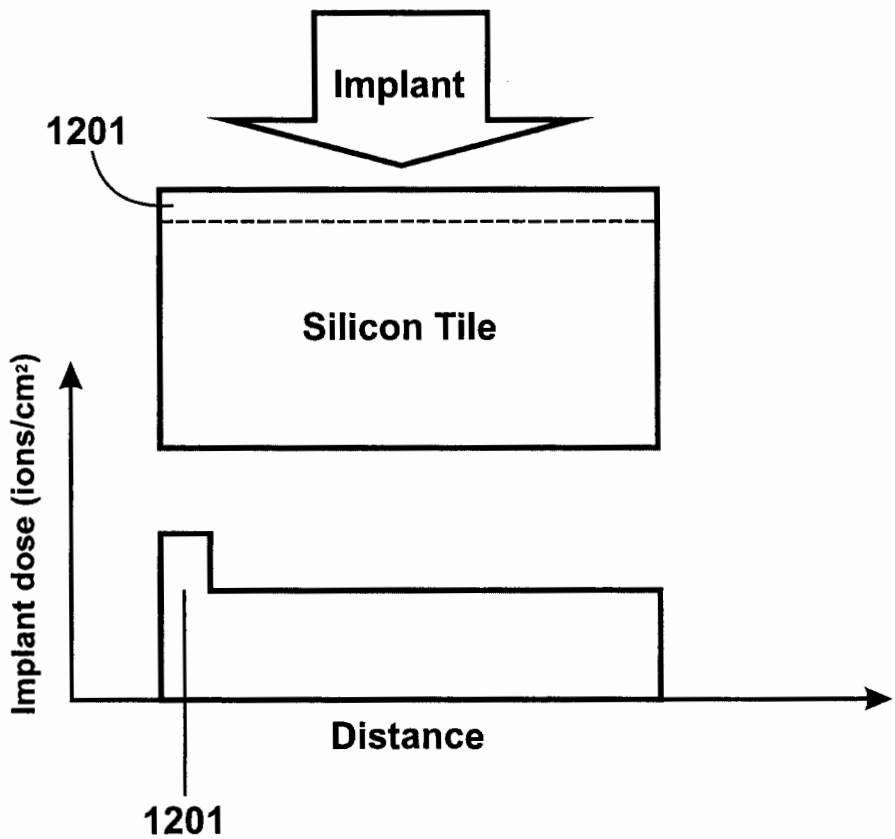


FIGURE 12(A)

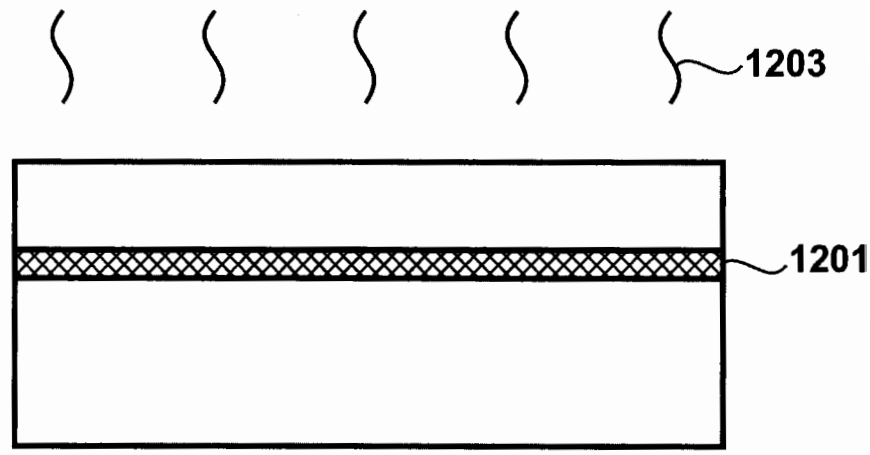


FIGURE 12(B)

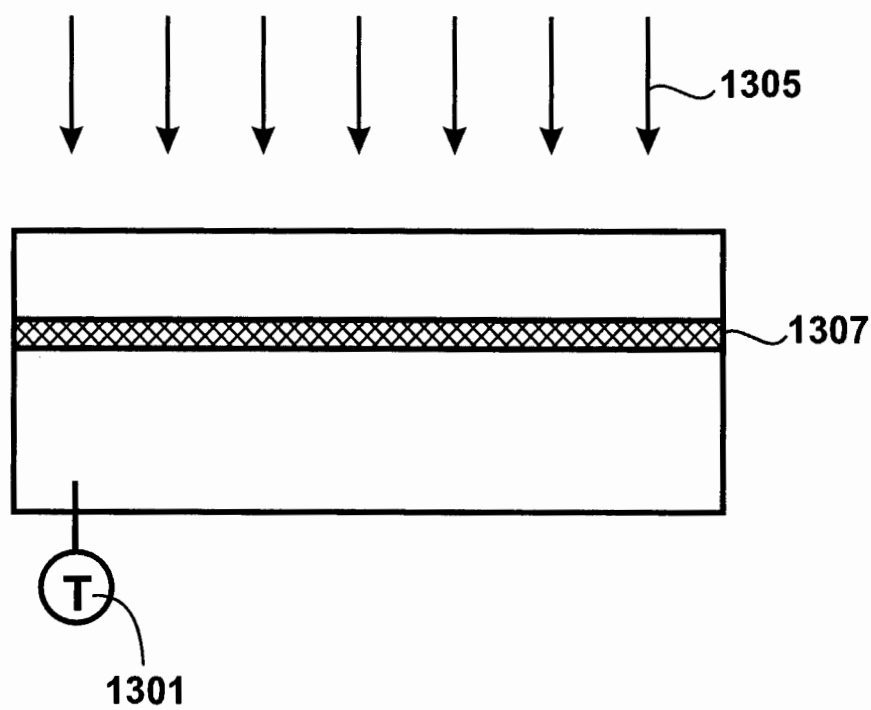


FIGURE 13

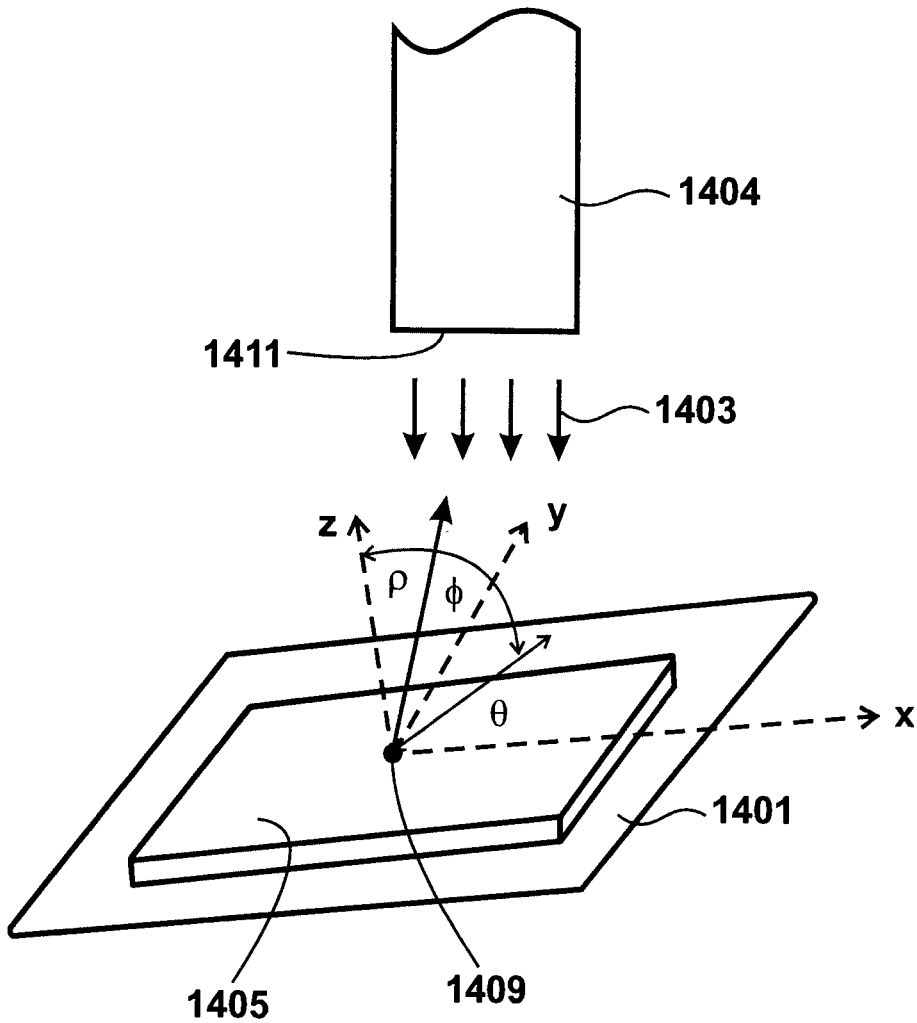


FIGURE 14

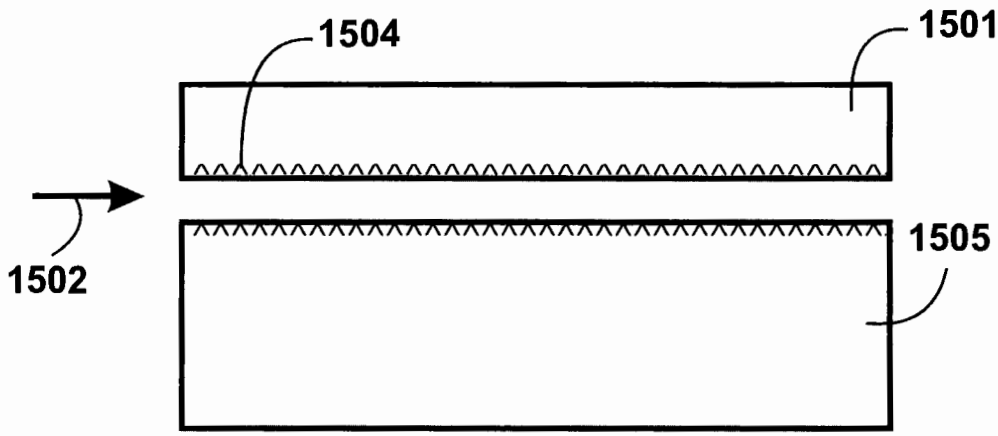


FIGURE 15

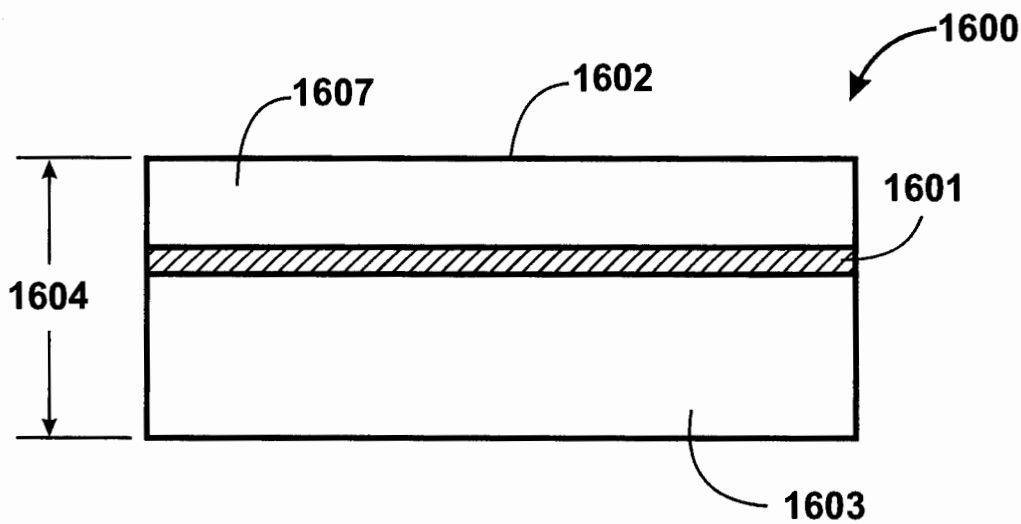


FIGURE 16

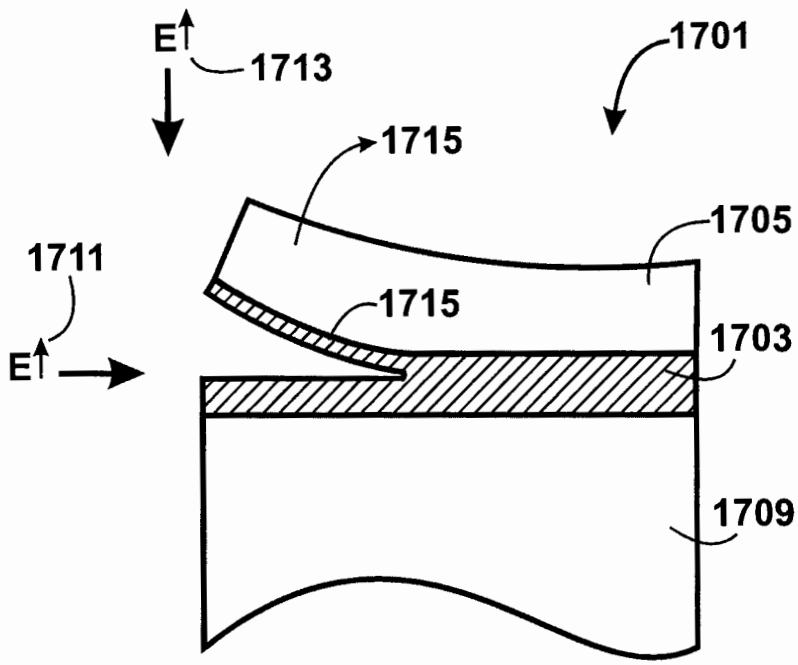


FIGURE 17

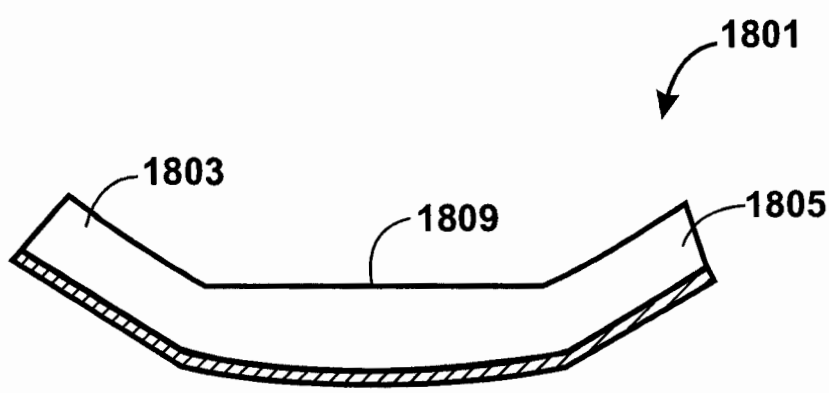


FIGURE 18

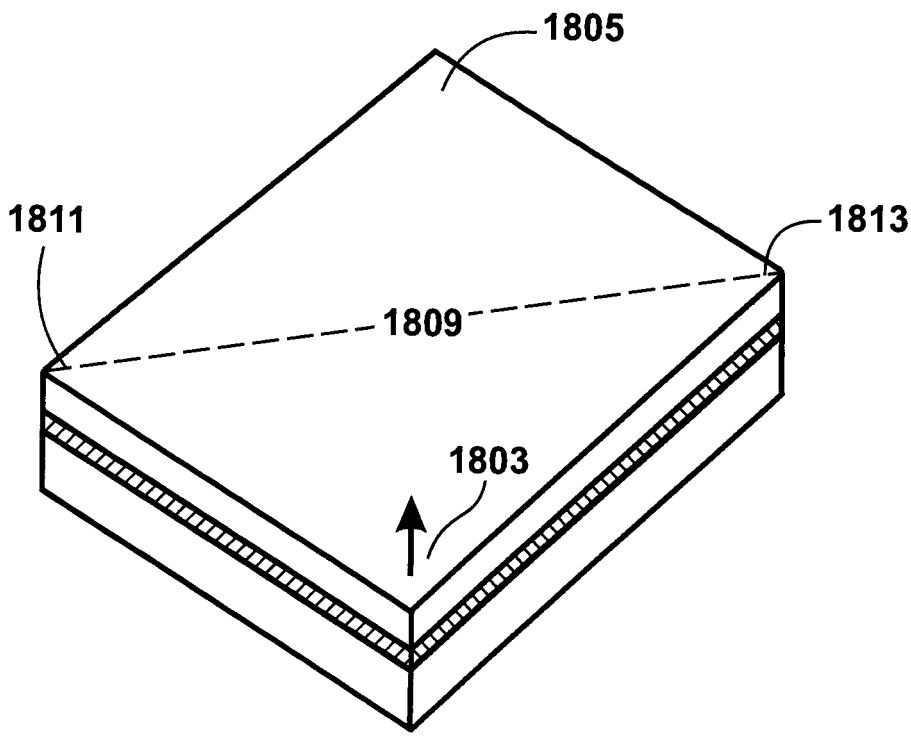


FIGURE 18A

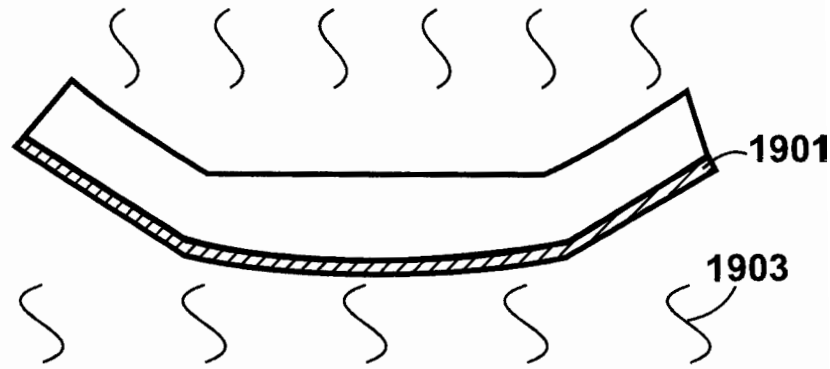


FIGURE 19

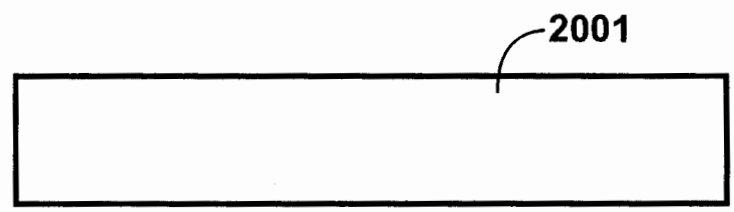


FIGURE 20

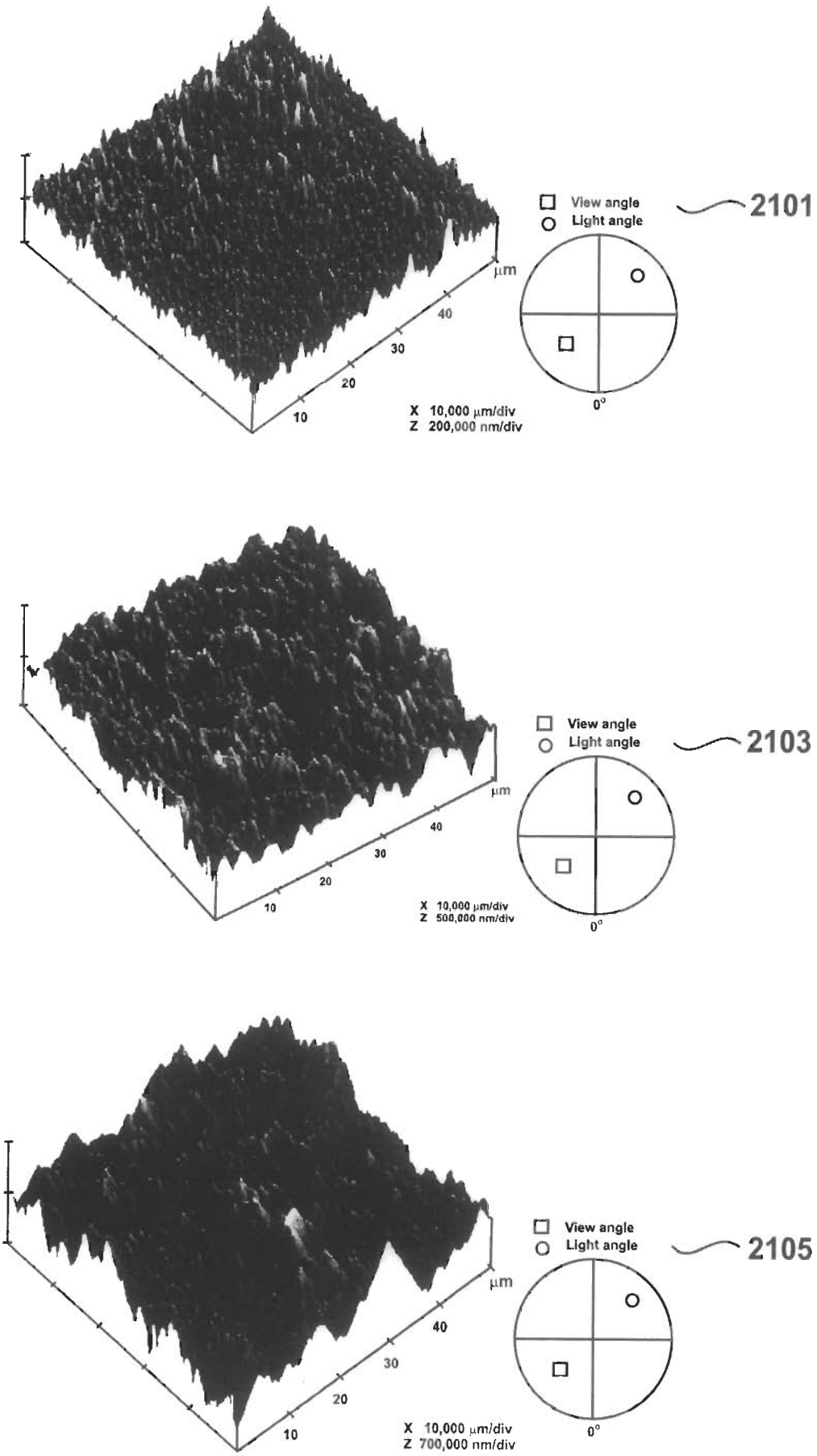

View angle
Light angle
2101
μm
10
20
30
40
0°
X 10,000 μm/div
Z 200,000 nm/div
View angle
Light angle
2103
μm
10
20
30
40
0°
X 10,000 μm/div
Z 500,000 nm/div
View angle
Light angle
2105
μm
10
20
30
40
0°
X 10,000 μm/div
Z 700,000 nm/div

FIGURE 21

Multiple DFT Transfer (117 μm)

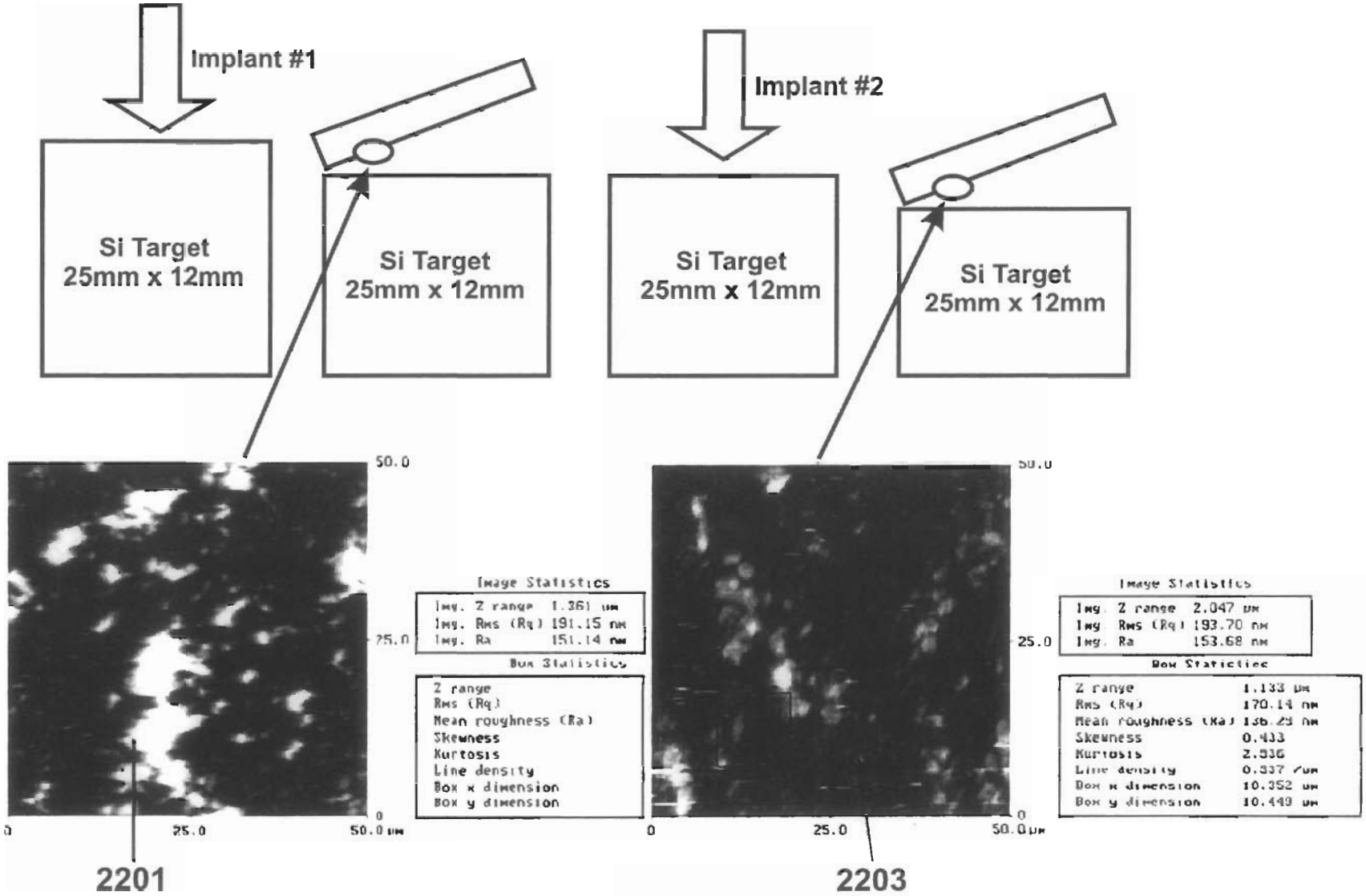
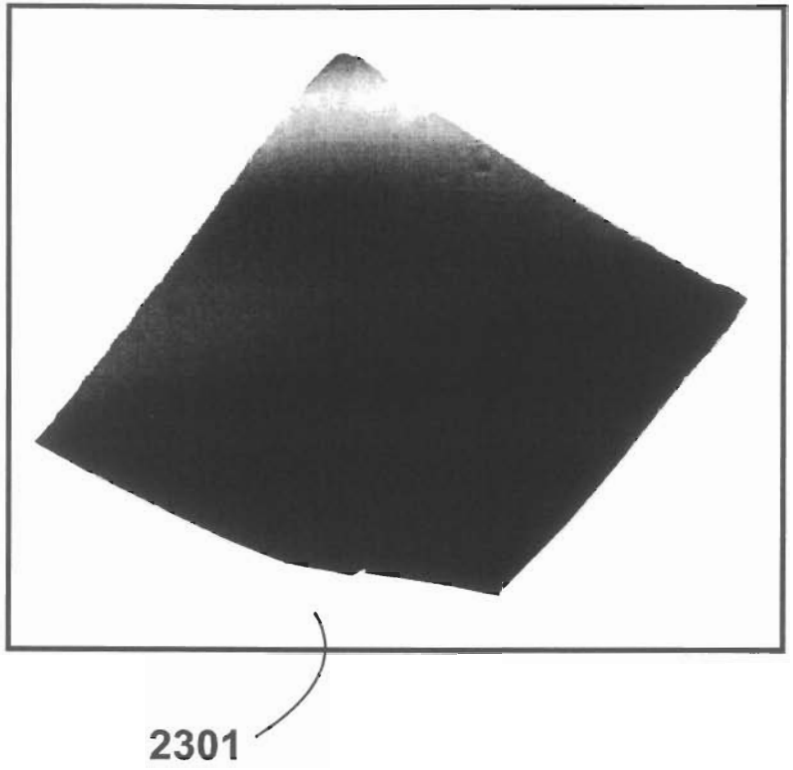
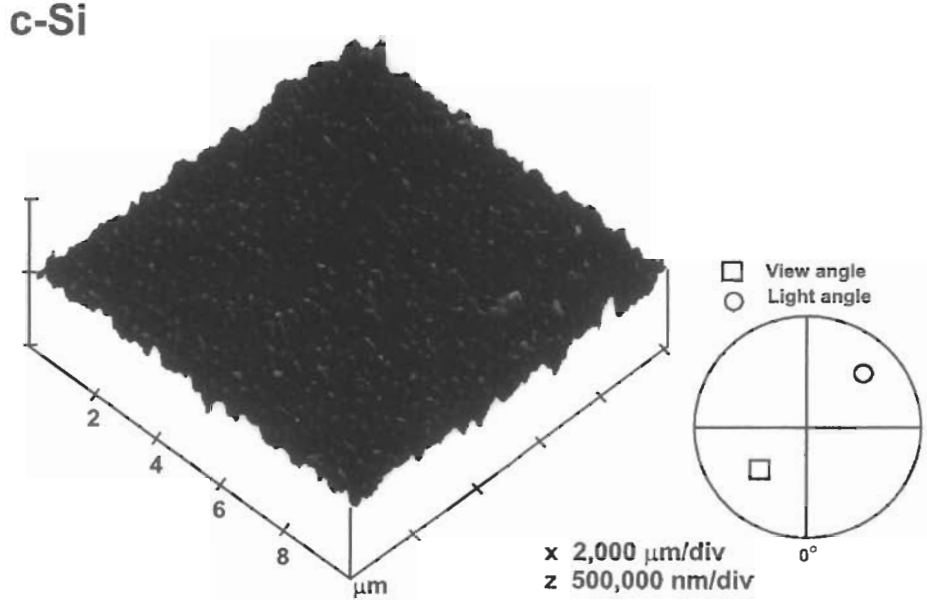


FIGURE 22


2301


c-Si
2
4
6
8
µm
View angle
Light angle
0°
x 2,000 µm/div
z 500,000 nm/div

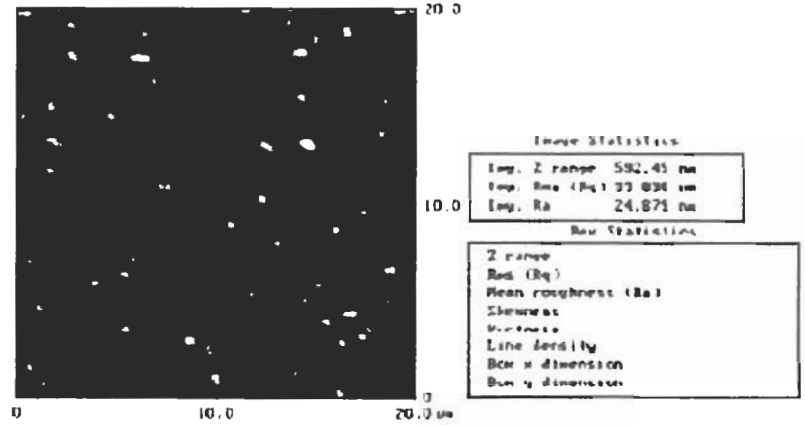
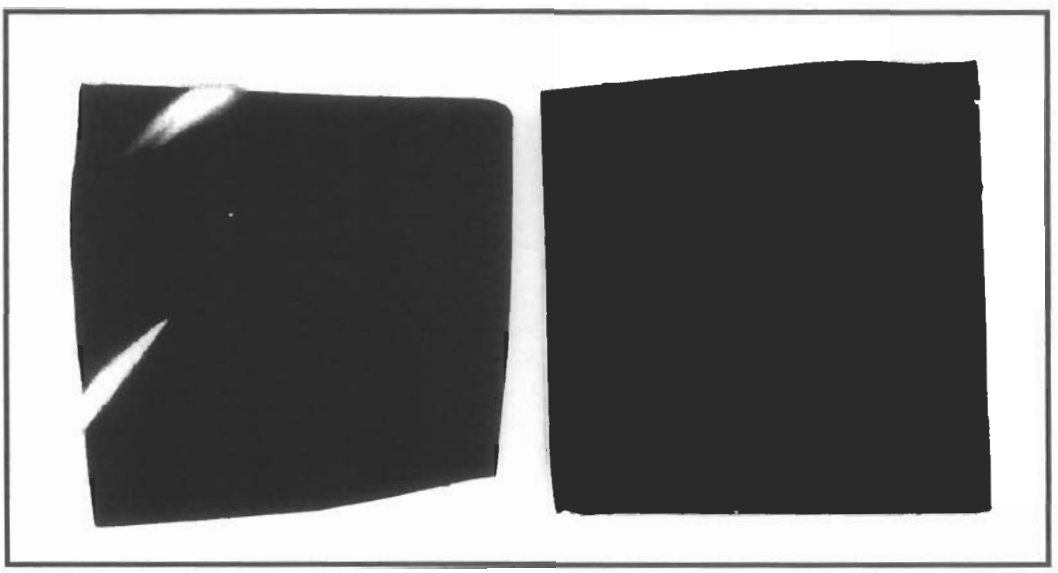

20.0
10.0
0
0
10.0
20.0 µm

FIGURE 23



c-Si

15 μm film

Silicon Donor

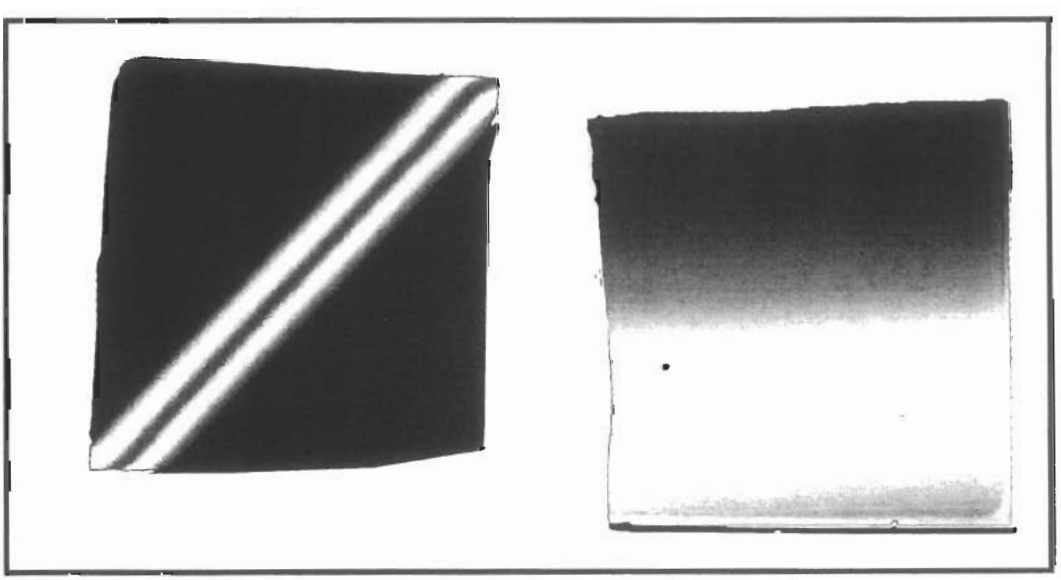


FIGURE 24

Mc-Si

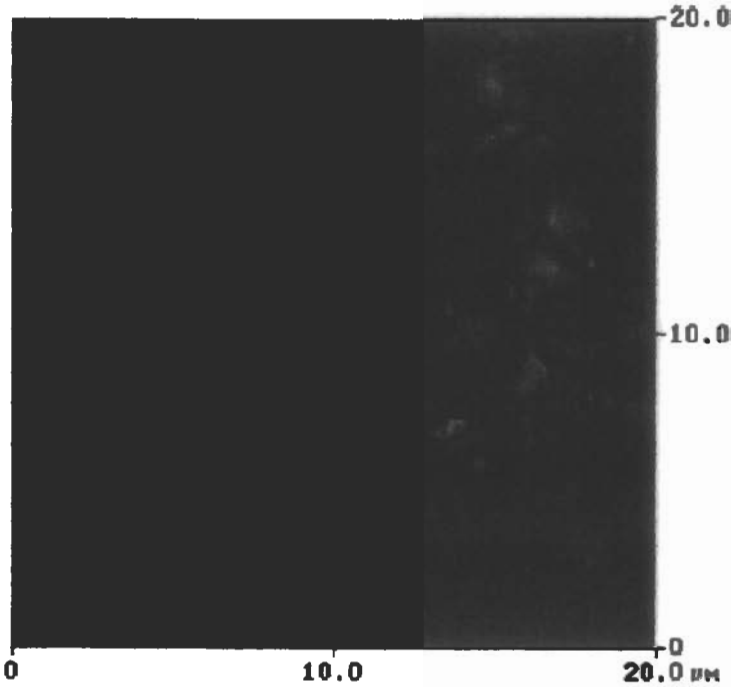
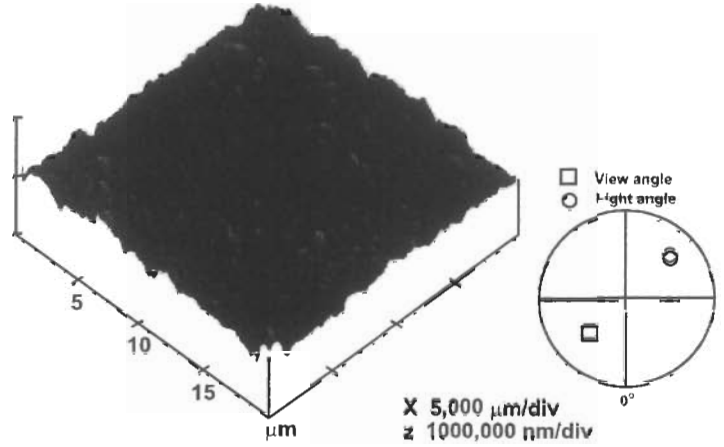


Image Statistics

Img. Z range	632.27 nm
Img. Rms (Rq)	79.980 nm
Img. Ra	63.622 nm



As-Cleaved Film Surface

FIGURE 25